

SEMI F68-1101 (Reapproved 1108)

TEST METHOD FOR DETERMINING PURIFIER EFFICIENCY

This standard was technically approved by the global Facilities and Gases Committees. This edition was approved for publication by the global Audits and Reviews Subcommittee on August 29, 2008. It was available at www.semi.org in October 2008 and on CD-ROM in November 2008. Originally published November 2001.

1 Purpose

1.1 The purpose of this document is to define a test method to quantify the efficiency of a purifier for removal of an active gaseous impurity from a matrix gas.

2 Scope

2.1 To determine the efficiency of a gas purifier to remove a given impurity species. Efficiency tests are performed by adding ppm levels of gaseous impurities to a pure matrix gas and monitoring the effluent of the test purifier for active impurity species. Tests are done at supplier recommended flow rate, operating temperature and pressure.

2.2 To establish a method of determining instantaneous purifier efficiency.

2.3 The test method applies to point of use (POU) and large scale purifiers.

2.4 This method is for UHP efficient removal of low-level contaminants.

NOTICE: This standard does not purport to address safety issues, if any, associated with its use. It is the responsibility of the users of this standard to establish appropriate safety and health practices and determine the applicability of regulatory or other limitations prior to use.

3 Limitations

3.1 The inherent limitation to this method is the limit of detection (LOD) of the analytical instrument employed by the user.

3.2 This test method can only be used to compare purifier efficiency results if the user application for flow rate, pressure, and temperature are the same as the test conditions. Different user and/or different operating conditions may result in different purifier performance results.

3.3 In testing mixtures of impurities, some impurities may influence the efficiency results of other impurities. Discussion with the manufacturer is highly recommended prior to testing.

3.4 The test method does not apply to particulates.

3.5 This test method will provide efficiency information only for impurities that are used in the challenge gas.

4 Referenced Standards and Documents

4.1 SEMI Standards

SEMI E29 — Standard Terminology for the Calibration of Mass Flow Controllers and Mass Flow Meters

SEMI F6 — Guide for Secondary Containment of Hazardous Gas Piping Systems

SEMI F22 — Guide for Gas Distribution Systems

SEMI F33 — Test Method for Calibration of Atmospheric Pressure Ionization Mass Spectrometer (APIMS)

4.2 ANSI Standards¹

ANSI B46.1 — Surface Texture (Surface Roughness, Waviness, and Lay)

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NOTICE: Unless otherwise indicated, all documents cited shall be the latest published versions.

5 Terminology

5.1 Abbreviations and Acronyms

- 5.1.1 *APIMS* — atmospheric pressure ionization mass spectrometer
- 5.1.2 °C — degrees Celsius
- 5.1.3 *DUT* — device under test
- 5.1.4 °F — degrees Fahrenheit
- 5.1.5 *in* — inch
- 5.1.6 *kPa* — kiloPascal
- 5.1.7 *LOD* — limit of detection
- 5.1.8 *m* — meter
- 5.1.9 *MFC* — mass flow controller
- 5.1.10 *NMHC* — non methane hydrocarbons
- 5.1.11 *POU* — point of use
- 5.1.12 *ppb* — parts per billion, volume basis
- 5.1.13 *ppm* — parts per million, volume basis
- 5.1.14 *psi* — pounds per square inch
- 5.1.15 *psia* — pounds per square inch absolute
- 5.1.16 *psig* — pounds per square inch gauge
- 5.1.17 R_a — surface roughness average (as defined in ANSI B46.1)
- 5.1.18 $R_{a,max}$ — surface roughness maximum (as defined in ANSI B46.1)
- 5.1.19 *s* — second
- 5.1.20 *sccm* — standard cubic centimeters per minute
- 5.1.21 *slpm* — standard liters per minute
- 5.1.22 *UHP* — ultra high purity

5.2 Definitions

- 5.2.1 *activation* — the process of initially preparing the purifier media to be chemically reactive with gas impurities.
- 5.2.2 *activation temperature* — temperature at which DUT was initially prepared.
- 5.2.3 *atmospheric pressure ionization mass spectrometer (APIMS)* — an instrument consisting of an atmospheric pressure ion source where gas phase impurities are ionized via charge exchange reactions with the bulk gas. These ions are directed into a vacuum chamber where they are then separated by a mass analyzer and detected by an electron multiplier.
 - 5.2.3.1 *ion source* — the section of a mass spectrometer used to generate sample ions by electron impact, chemical ionization, or charge exchange.
 - 5.2.3.2 *mass analyzer* — a device that utilizes electric and/or magnetic fields to separate charged particles or ions according to their mass-to-charge (m/e) ratios. Examples of mass analyzers include quadrupole, magnetic and/or electric sector, time of flight, and ion traps.
 - 5.2.3.3 *electron multiplier* — a device that detects and amplifies electro-magnetic phenomena such as positive/negative ions.

5.2.4 *back pressure regulator* — a self-contained device, consisting of a mechanical or electrical sensor and control device, commonly used in the semiconductor industry to maintain a constant pressure upstream of the regulator.

5.2.5 *breakthrough* — the point in time when an individual impurity level in the purifier effluent exceeds the level specified by the manufacturer. Typically in the range of 1–100 ppb.

5.2.6 *challenge gas* — a gas mixture containing high levels of gas impurities. Typically, a challenge gas has impurities of between 500 ppm to 1% which is used to shorten the test duration; however, challenges in the range of 1–10 ppm for the impurities is more representative.

5.2.7 *efficiency* — a measure of the ability of a purifier to remove active impurities from a matrix gas stream. It is calculated as the ratio of the difference between the inlet concentration and the concentration of impurity leaving the purifier to the concentration of impurity entering the purifier.

5.2.8 *gaseous impurities* — gas phase elements and compounds in the gas stream other than the process or base gas.

5.2.9 *impurity analyzer* — an appropriate analyzer to measure the concentration of desired impurities in a gas stream from the ppm to the percent (%) concentration range.

5.2.10 *inert gas* — a gas, which at ambient conditions, does not react chemically with other materials or chemicals.

5.2.11 *limit of detection (LOD)* — lowest concentration that can be detected by an instrument. LOD is typically defined as three times the standard deviation of the mean noise level (see SEMI F6, lower detectable limit of instrument).

5.2.12 *mass flow controller (MFC)* — a self-contained device, consisting of a mass flow transducer, control valve, and control and signal-processing electronics, commonly used in the semiconductor industry to measure and regulate the mass flow of gas (as defined in SEMI E29).

5.2.13 *pure gas* — an inert gas, minimum purity of 99.9995%, and less than 1 ppb of each impurity that is specified to be removed by the DUT.

5.2.14 *purifier* — generally a catalytic (getter, reactive), resinous, or diatomaceous material within a pressure vessel which removes particulate and/or trace gas impurities from a gas stream (as defined in SEMI F22).

5.2.15 *purifier capacity* — the total quantity of each trace gas impurity that may be sorbed by the purifier media. Defined as liters impurity/liter purifier media.

5.2.16 *regeneration* — the process of reactivating the purifier media.

5.2.17 *test duration* — total time required to complete the test procedure.

5.2.18 *test flow rate* — flow rate through DUT (slpm).

5.2.19 *test pressure* — pressure immediately upstream of the DUT.

5.2.20 *test temperature* — operating temperature of DUT.

5.2.21 *ultratrace analytical instrumentation* — instrumentation that has sufficient sensitivity to measure all impurities of interest at the specified level of the customer, the ppb or sub-ppb level.

5.2.22 *zero gas* — nitrogen, argon, helium or hydrogen with an estimated level an order of magnitude, or more, lower than the lowest calibration point for each impurity of interest (as defined in SEMI F33).

6 Summary of Method

6.1 This method will allow a user to quantify the impurity efficiency of a point-of-use (POU) or large scale purifier.

7 Safety Precautions

7.1 This test method may involve hazardous materials, operations, and equipment. The test method does not purport to address the safety considerations associated with its use. It is the responsibility of the user to establish appropriate safety and health practices and determine the applicability of regulatory limitations before using this method.

7.2 Exhaust from the DUT should be properly vented.